

NON-LINEAR CHARACTERISATION AND MODELLING OF CMOS

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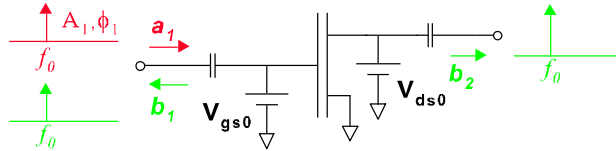
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Outline

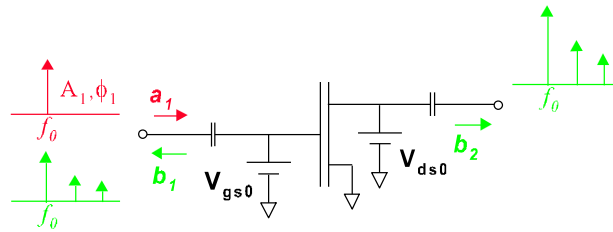
- **Introduction**
 - non-linear CMOS models
 - non-linear network measurement system (NNMS)
- **Verification of non-linear CMOS models**
 - single- and multi-tone excitation at 50 Ω load
 - two-tone excitation with small frequency offset (= intermodulation testing) combined with loadpull
- **NNMS based non-linear device modelling**
 - device's state-functions obtained by *optimisation*
 - direct *extraction* of the device's state functions
- **Conclusions**

Measurement techniques

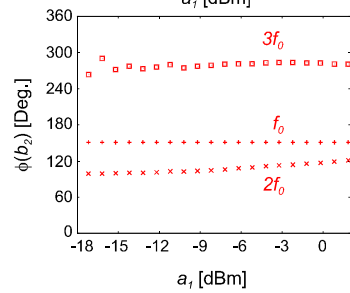
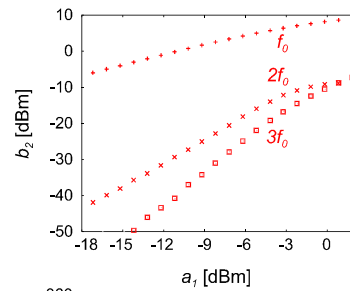
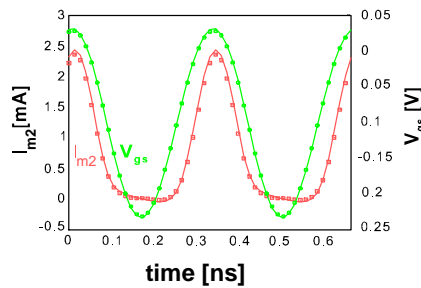
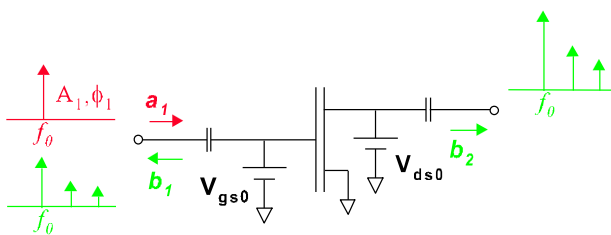
Vector Network Analyzer (VNA)



Non-linear Network Measurement System (NNMS)

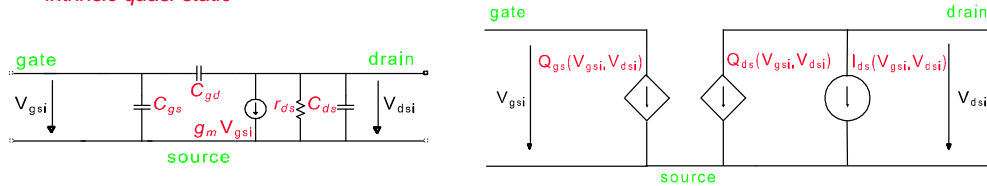


Vectorial large-signal measurements



Non-linear CMOS modelling techniques

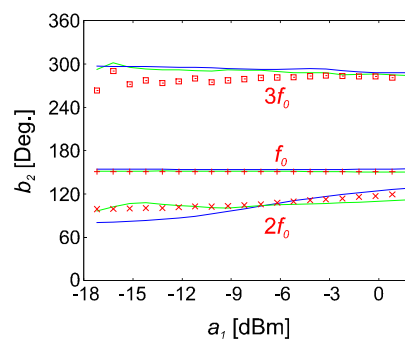
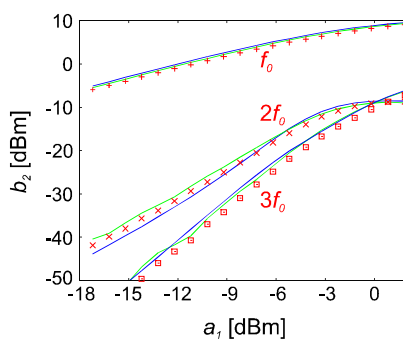
intrinsic quasi-static



linear \Leftrightarrow non-linear

- **Compact models:**
 - state-functions represented by *analytical function*
 - based on DC, low-frequency C-V and possibly HF S-par. meas.
- **Table-based models:**
 - *tabulated* state-functions
 - based on HF S-par. and possibly DC meas.

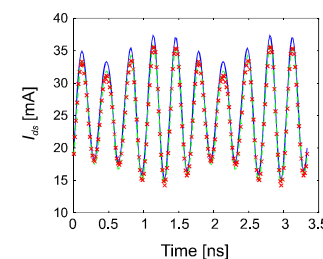
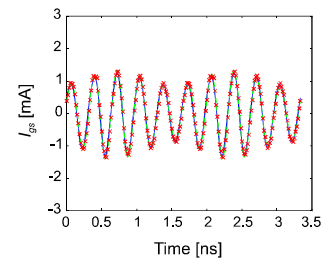
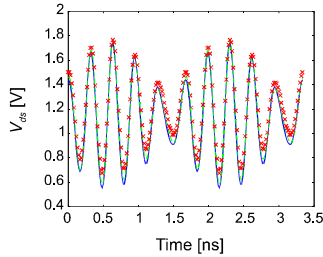
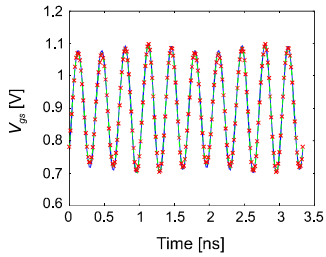
CMOS non-linear model verification: single-tone excitation



meas table-based model BSIM3 model

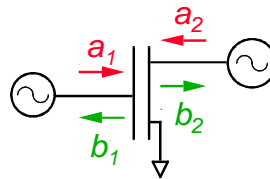
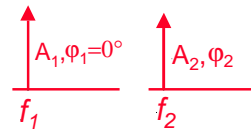
0.18 μm , 146 μm Si nMOSFET
 $f_0=3.6$ GHz - $V_{gsDC}=0.6$ V - $V_{dsDC}=1.2$ V

CMOS non-linear model verification: two-tone excitation



meas table-based model BSIM3 model

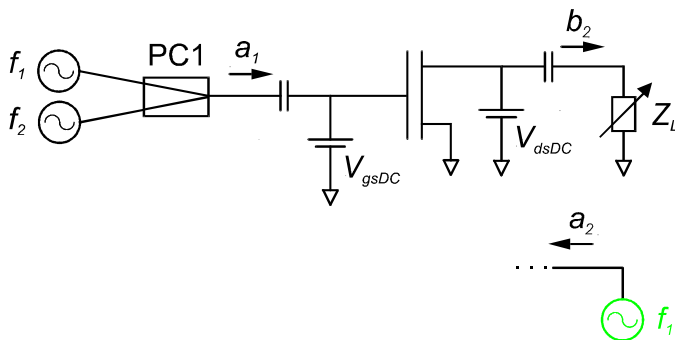
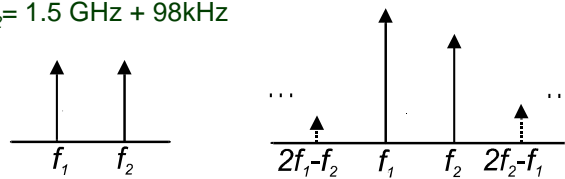
two-tone example



0.18 μm x 146 μm nMOST
 $V_{gsDC} = 0.9 \text{ V}$, $V_{dsDC} = 1.2 \text{ V}$
 $f_1 = 3 \text{ GHz}$, $a_1 = -10 \text{ dBm}$
 $f_2 = 3.6 \text{ GHz}$, $a_2 = -7 \text{ dBm}$
 $\phi(a_2) - \phi(a_1) = 37^\circ$

Measurement configuration

$f_1 = 1.5 \text{ GHz} - 98 \text{ kHz}$
 $f_2 = 1.5 \text{ GHz} + 98 \text{ kHz}$



loadpull

passive
 \hat{O}
 active

$$\Gamma_{L,f1} = a_{2,f1}/b_{2,f1}$$

$$\Gamma_{L,fi} \approx 0$$

CMOS non-linear model verification: IM3 & loadpull

Class A

	Meas. [dBm]	BSIM3 model [dBm]	table-based model [dBm]	Meas. [°]	BSIM3 model [°]	table-based model [°]
$b_{2,f1}$	3.1	4.1	3.9	31	34	32
$b_{2,f2}$	3.4	4.3	4.2	41	45	42
$b_{2,2f1-f2}$	-20.7	-20.3	-20.3	-156	-156	-157
$b_{2,2f2-f1}$	-19.5	-19.6	-19.5	-148	-135	-134

$$Z_{L,f1} = 36-j1, Z_{L,f2} = 66-j2$$

$$|a_{1,f1}| = |a_{1,f2}| = -7.3 \text{ dBm}$$

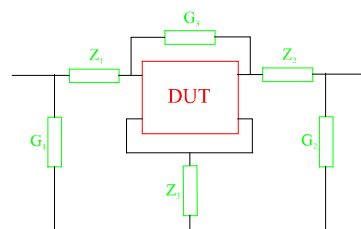
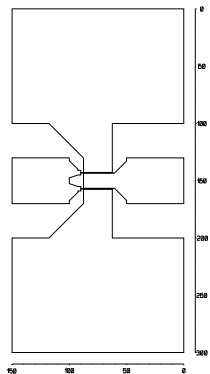
$$V_{gsDC} = 0.9 \text{ V}, V_{dsDC} = 1.2 \text{ V}$$

0.2 μm x 146 μm nMOSFET

De-embedding of access transmission lines

De-embedding of pad interconnections:

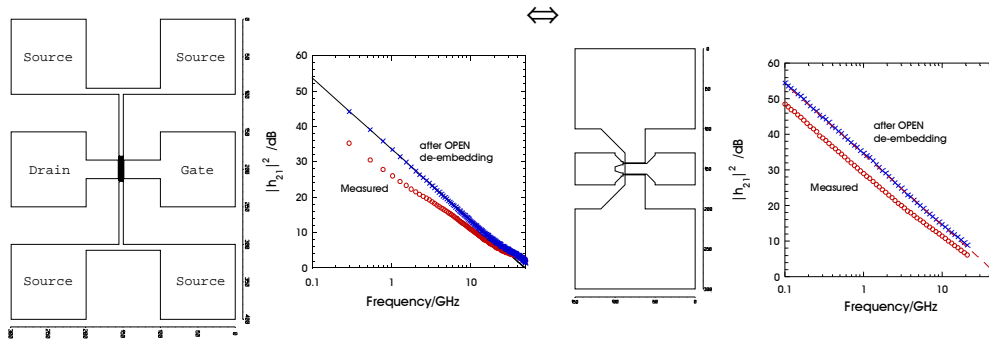
H. Cho and D. Burk, "A **three-step method** for the de-embedding of high-frequency S-parameter measurements", IEEE Trans. Electron Devices, pp. 1371-1375, 1991



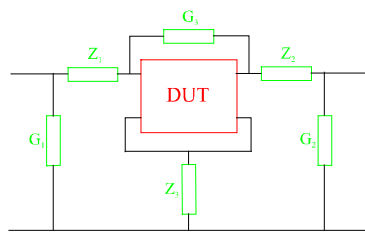
Measurement results — f_T

f_T should be extracted at low frequencies after de-embedding with (at least) an open structure

- Measured $|h_{21}|^2$ not necessarily -20dB/dec
- Transistor-layout influences measured $|h_{21}|^2$
- $|h_{21}|^2$ after de-embedding shows -20dB/dec, as expected



Importance of interconnections



$$Z_{L,f1} = 36-j1, Z_{L,f2} = 66-j2$$

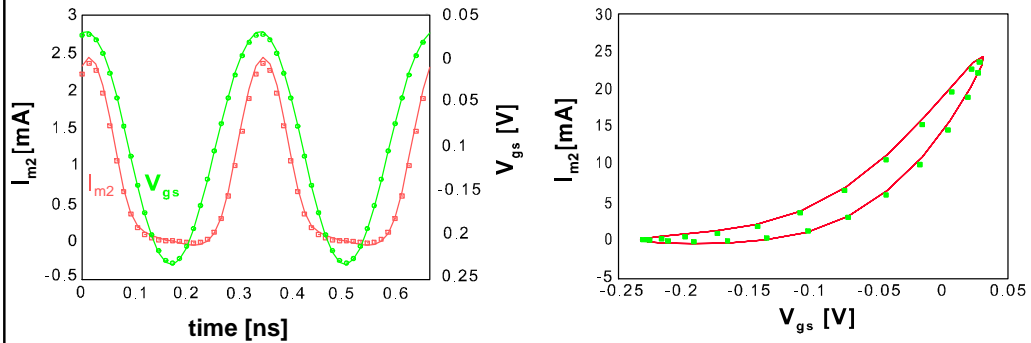
$$|a_{1,f1}| = |a_{1,f2}| = -7.3 \text{ dBm}$$

$$V_{gsDC} = 0.9 \text{ V}, V_{dsDC} = 1.2 \text{ V}$$

$$0.2 \mu\text{m} \times 146 \mu\text{m} \text{ nMOSFET}$$

	Meas. [dBm]	BSIM3 model incl. interc. [dBm]	BSIM3 model excl. interc. [dBm]	Meas. [°]	BSIM3 model incl. interc. [°]	BSIM3 model excl. interc. [°]
$b_{2,f1}$	3.1	4.1	4.7	31	34	42
$b_{2,f2}$	3.4	4.3	4.9	41	45	54
$b_{2,2f-f2}$	-20.7	-20.3	-19	-156	-156	-146
$b_{2,2f-f1}$	-19.5	-19.6	-18.2	-148	-135	-124

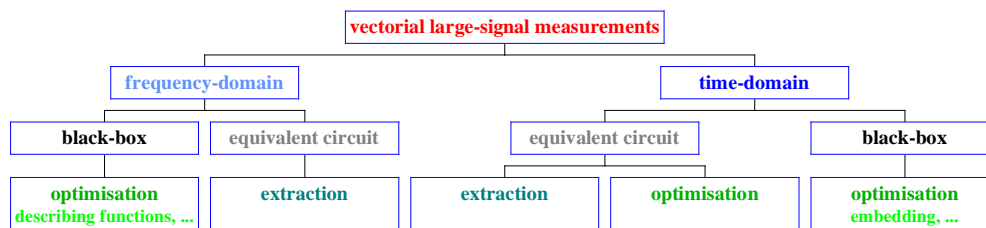
Non-linear model verification



Capacitive effects δ time shift between V_{gs} and I_{m2} waveforms
 δ (I_{m2} , V_{gs}) trace shows hysteresis

0.2 μm , 100 μm GaAs PHEMT (but similar behaviour for CMOS)
 $V_{dsDC}=2\text{ V}$ - $I_{ds}=3\text{ mA/mm}$ - $f_0=3\text{ GHz}$ - $P_{in}=-13.5\text{ dBm}$

Overview of different modelling techniques



Device's state functions by optimisation

Empirical & compact transistor models

- = state-functions are represented by analytical expression

$$Q_{gs}(V_{gsi}, V_{dsi}), I_{ds}(V_{gsi}, V_{dsi}), Q_{ds}(V_{gsi}, V_{dsi})$$

- often preferred by foundries due to limited number of parameters compared to table-based models
- technology dependent:
 - CMOS: e.g., BSIM3v3 model
 - HEMT: e.g., Chalmers model
- complexity analytical expression is often a compromise between number of parameters and accuracy over broad bias and frequency range

Device's state functions by optimisation

Parameter estimation by optimisation towards measurements:

- classical approach:
 - DC - C-V - S-parameters - amplitude spectral measurements at output
 - (-) several measurement systems: DC, VNA, spectrum analyser, ...
 - (-) consistent optimisation requires adequate software
- novel approach:
 - only vectorial large-signal measurements at input and output
 - 1 measurement system (NNMS) & 1 HB simulator with an optimiser
 - fast and accurate generation of device models under *real* operating conditions

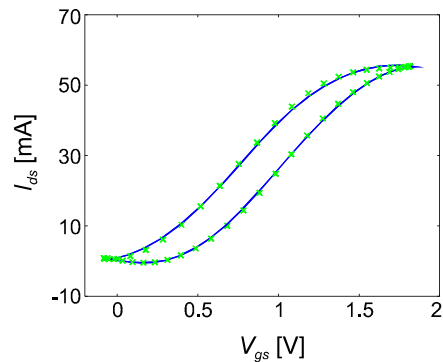
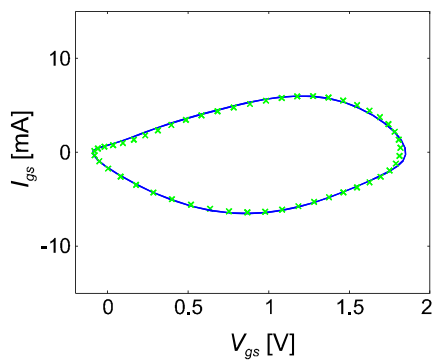
Empirical transistor model parameter estimation

empirical model: e.g., Chalmers model:

0.18 μm x 146 μm Si *n*MOSFET operated at class A ($V_{gsDC} = 0.9\text{ V}$ - $V_{dsDC} = 1.8\text{ V}$)

NNMS measurements at $f_0 = 3.6\text{ GHz}$ & varying P_{in}

results @ $P_{in} = 3.8\text{ dBm}$:



Conclusions

NNMS & non-linear MOSFET modelling:

- importance of *de-embedding* access transmission lines
- extended non-linear model *verification*
 - complex spectra / time-domain waveforms
 - at realistic operating conditions, e.g., intermodulation & loadpull
- *model building* directly based on large-signal measurements
 - state-functions obtained by *optimisation*
 - » applicable to empirical/compact device models & neural networks
 - » preferably used to model device for specific applications
 - direct *extraction* of state-functions
 - » preferably used to obtain 'general' model for device

Literature

- [1] J. Verspecht *et al.*, "Accurate on wafer measurement of phase and amplitude of the spectral components of incident and scattered voltage waves at the signal ports of a nonlinear microwave device", IEEE MTT-S Int. Microwave Symp. Digest, 1995, pp. 1029-1032.
- [2] E. Vandamme *et al.*, "Reliable extraction of RF figures-of-merit for MOSFETs", 29th European Solid-State Device Research Conference, 1999, pp. 660-663.
- [3] D. Schreurs *et al.*, "Easy and accurate empirical transistor model parameter estimation from vectorial large-signal measurements", IEEE Int. Microwave Symp. Digest, 1999, pp. 753-756.
- [4] D. Schreurs *et al.*, "Large-signal modelling and measuring go hand-in-hand: accurate alternatives to indirect S-parameter methods", International Journal of RF and Microwave Computer-Aided Engineering 10 (2000), pp. 6-18.
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- [6] D. Schreurs *et al.*, "Verification of non-linear MOSFET models by intermodulation measurements under loadpull conditions", 55th Automatic RF Techniques Group Conference, June 2000, pp. 58-62.
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- [8] E. Vandamme *et al.*, "Impact of probe-to-pad contact degradation on the high frequency characteristics of RF MOSFETs and guidelines to avoid it", International Journal of RF and Microwave Computer Aided Engineering, publication scheduled for 2001.
- [9] E. Vandamme *et al.*, "Improved three-step de-embedding method to accurately account for the influence of pad parasitics in silicon RF test-structures", IEEE Transactions on Electron Devices, publication scheduled for 2001.